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PATENT

Atty. Dkt. No. AMAT/4714.C1/CP1/WCVD/PJS

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Xi, et al.

Serial No.: 10/762,764

Confirmation No.: 3117

Filed: January 22, 2004

For: Method and Apparatus for  
Depositing Refractory Metal  
Layers Employing Sequential  
Deposition Techniques to Form a  
Nuclear Layer

Group Art Unit: 2829

Examiner: David A. Zameke

MAIL STOP AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF FACSIMILE  
TRANSMISSION UNDER 37 CFR 1.8I hereby certify that this correspondence and the documents  
referred to as attached therein are being facsimile transmitted to  
the U.S. Patent and Trademark Office to the fax number  
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to the attention of the named Examiner, on the date below.5/2/05  
Date[Signature]  
Signature

## RESPONSE TO FINAL OFFICE ACTION DATED MARCH 2, 2005

In response to the Final Office Action dated March 2, 2005, having a shortened statutory period for response set to expire on June 2, 2005, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/4714.C1/KMT for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. Remarks begin on page 5 of this paper.

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